

**Notice of References Cited**Applicant/Patent  
**Sandhu et al.**Application/Control No.  
**08/636,069**Examiner  
**Erik Kielin**Art Unit  
**2813**

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**U.S. PATENT DOCUMENTS**

	Document Number Country Code-Number-Kind Code	Date MM-YYYY <sup>1</sup>	Name	Classification <sup>2</sup>	
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

	Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages
U	the article by Inoue et al. entitled, "Growth of SiO <sub>2</sub> thin film by double-excitation photoinduced chemical vapor deposition incorporated with microwave excitation of oxygen" Journal of Applied Physics 64(11), 1 Dec. 1988.
V	
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<sup>1</sup> A copy of this reference is not being furnished with this Office action. See MPEP § 707.05(a).<sup>1</sup> Dates in MM-YYYY format are publication dates.<sup>2</sup> Classifications may be U.S. or foreign.